



**THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Cho et al.

Atty Docket No.: NOVLP089/NVLS-  
002886/002887

Application No.: 10/800,377

Examiner: Not yet assigned

Filed: March 11, 2004

Group: 2812

Title: METHOD AND APPARATUS FOR UV  
EXPOSURE OF LOW DIELECTRIC CONSTANT  
MATERIALS FOR POROGEN REMOVAL AND  
IMPROVED MECHANICAL PROPERTIES

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on September 28, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

Tara Hayden

**REQUEST FOR STATUS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant hereby requests status of the above-referenced patent application. This application was filed on March 11, 2004 and no response has been received as of this date.

Respectfully submitted,

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